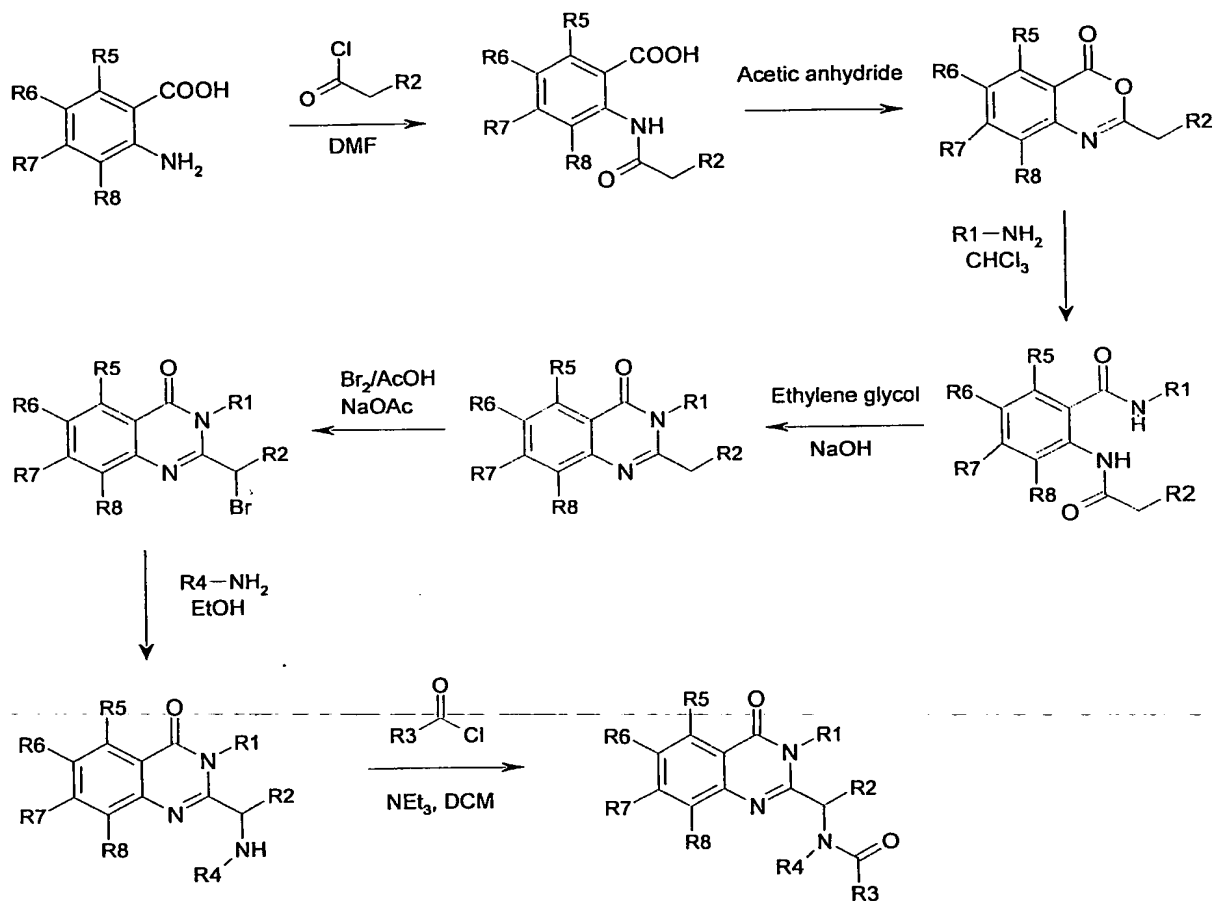


Figure 1

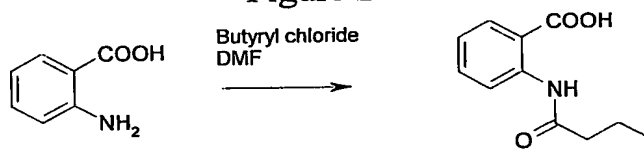
5



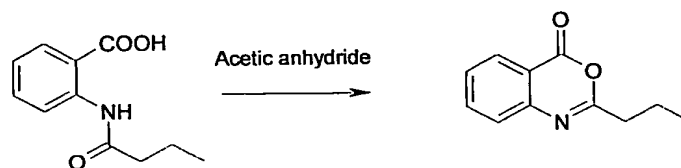
00827T 46842460

Figure 2

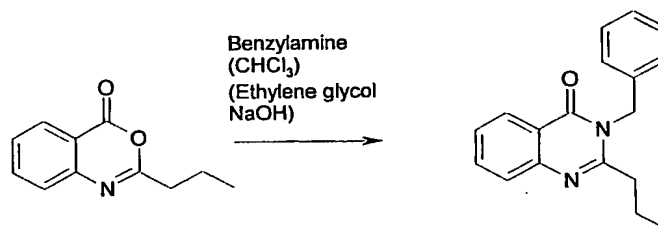
Step 1:



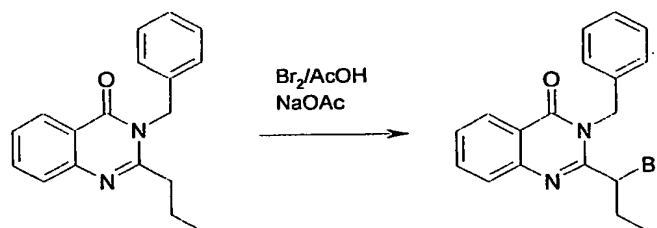
Step 2:



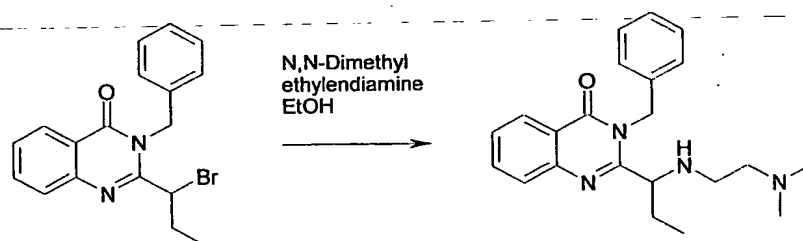
Step 3:



Step 4:



Step 5:



Step 6:

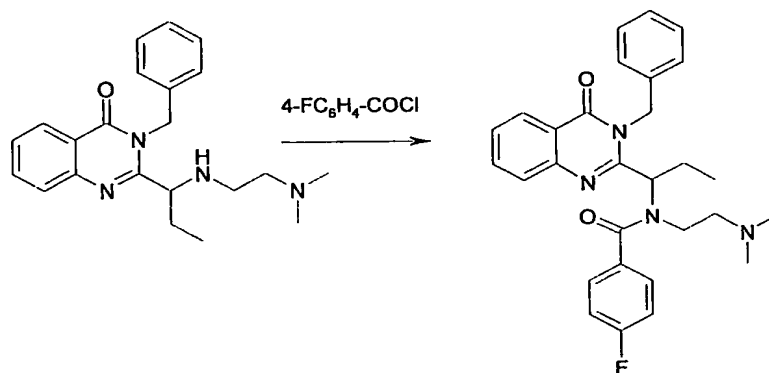


Figure 3

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	Activity
						Cl-X <sub>7</sub>	%I > 35% @ 40 uM
							%I > 35% @ 40 uM
							%I > 35% @ 40 uM

Figure 3 (continued)

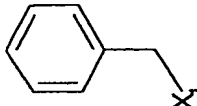

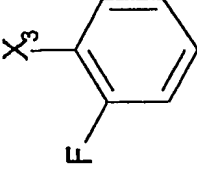
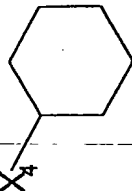
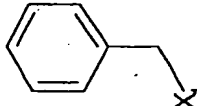

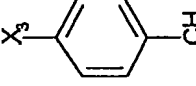
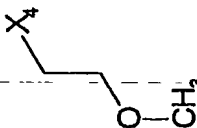
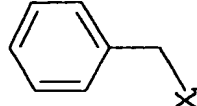

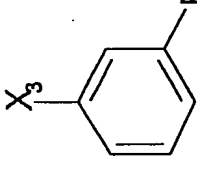
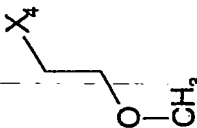
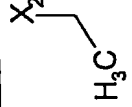
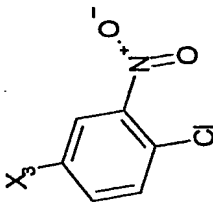
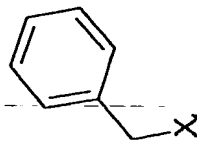

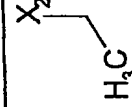
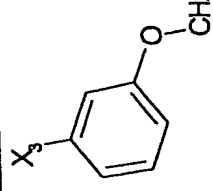
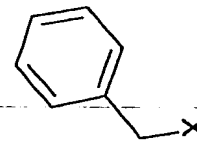

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM



Figure 3 (continued)

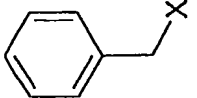

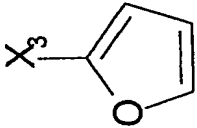
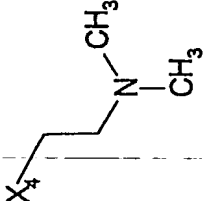
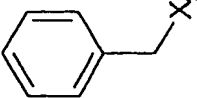
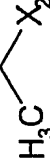
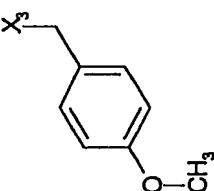
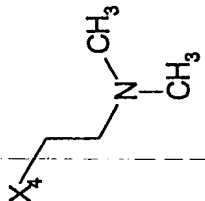
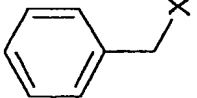

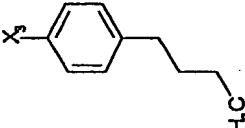
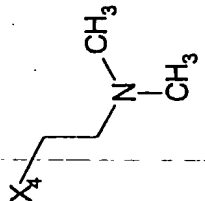
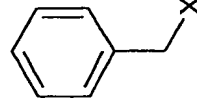

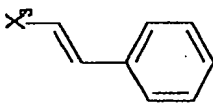
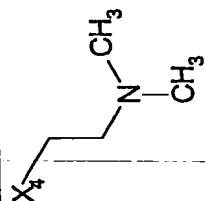
R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM



Figure 3 (continued)


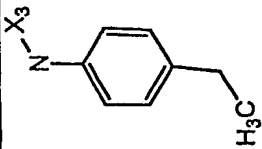
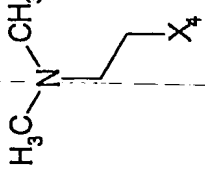

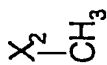
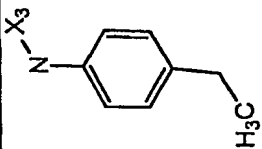
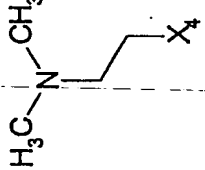

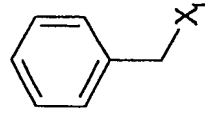

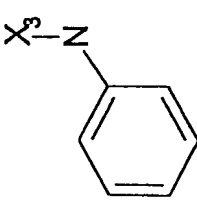
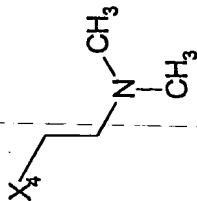
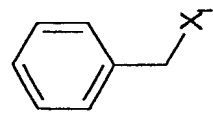

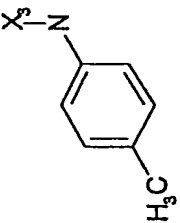
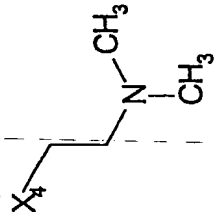
R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
	H <sub>3</sub> C-X <sub>2</sub>							%I > 35% @ 40 uM
	H <sub>3</sub> C-X <sub>2</sub>							%I > 35% @ 40 uM
	H <sub>3</sub> C-X <sub>2</sub>							%I > 35% @ 40 uM
	H <sub>3</sub> C-X <sub>2</sub>							%I > 35% @ 40 uM
	H <sub>3</sub> C-X <sub>2</sub>							%I > 35% @ 40 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
	H <sub>3</sub> C-X <sub>2</sub>							%I > 35% @ 40 uM
	H <sub>3</sub> C-X <sub>2</sub>							%I > 35% @ 40 uM
	H <sub>3</sub> C-X <sub>2</sub>							%I > 35% @ 40 uM
	H <sub>3</sub> C-X <sub>2</sub>							%I > 35% @ 40 uM
	X <sub>2</sub> -CH <sub>2</sub> -CH <sub>3</sub>							%I > 35% @ 40 uM

Figure 3 (continued)

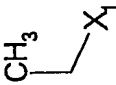

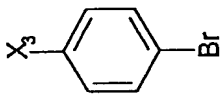
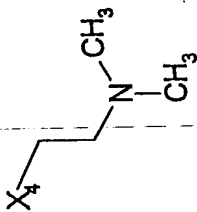

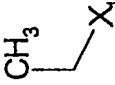

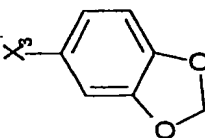
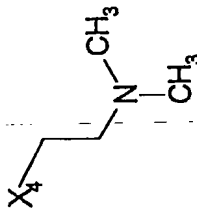

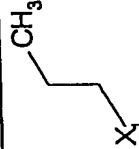

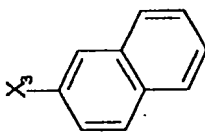
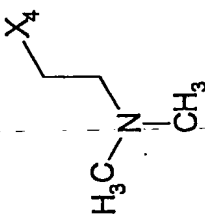
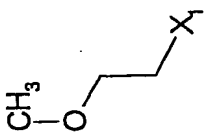

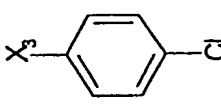
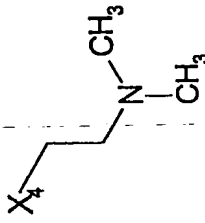
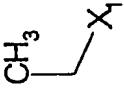
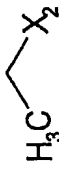
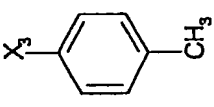
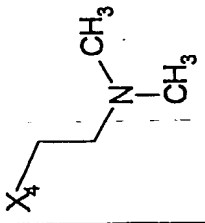
R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM



Figure 3 (continued)


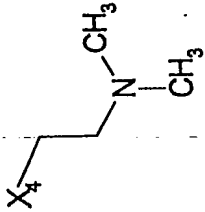
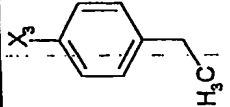
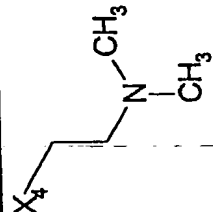
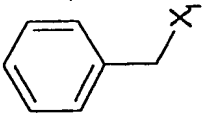
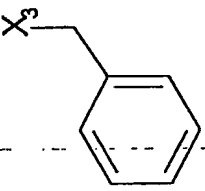
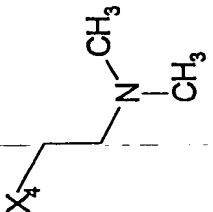
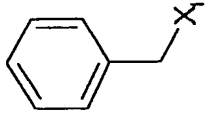
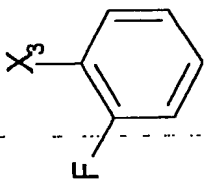
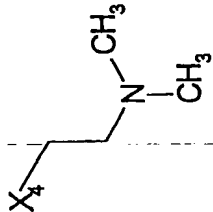
R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
H <sub>3</sub> C-X <sub>1</sub>	H <sub>3</sub> C-X <sub>2</sub>					X <sub>7</sub> -Cl		%I > 35% @ 40 uM
H <sub>3</sub> C-X <sub>1</sub>	H <sub>3</sub> C-X <sub>2</sub>					X <sub>7</sub> -Cl		%I > 35% @ 40 uM
	H <sub>3</sub> C-X <sub>2</sub>							%I > 35% @ 40 uM
	H <sub>3</sub> C-X <sub>2</sub>							%I > 35% @ 40 uM

Figure 3 (continued)

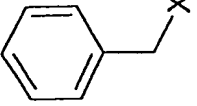

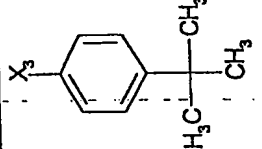
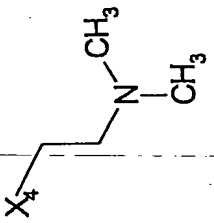
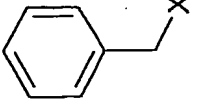

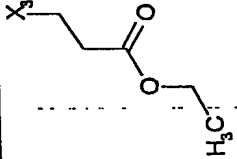
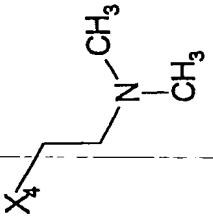
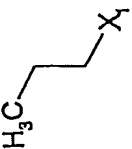
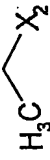
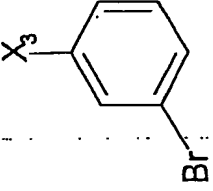
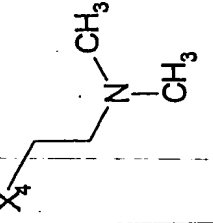
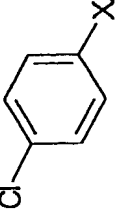

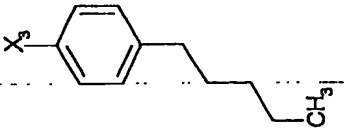
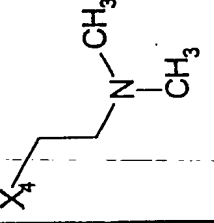
R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
	$\text{H}_3\text{C}-\text{X}_2$							%I > 35% @ 40 uM
	$\text{H}_3\text{C}-\text{X}_2$							%I > 35% @ 40 uM
	$\text{X}_2-\text{CH}_2$							%I > 35% @ 40 uM
	$\text{H}_3\text{C}-\text{X}_2$							%I > 35% @ 40 uM
	$\text{H}_3\text{C}-\text{X}_2$							%I > 35% @ 40 uM

Figure 3 (continued)

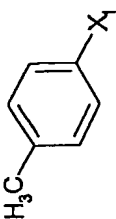

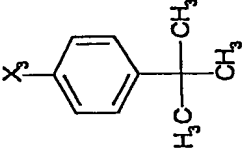
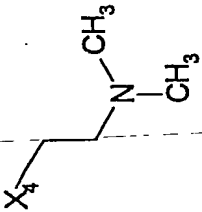
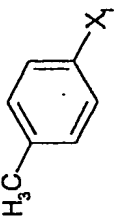

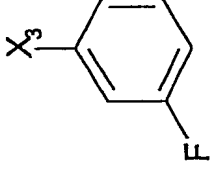
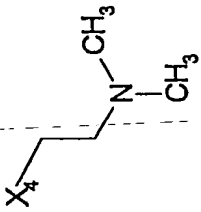
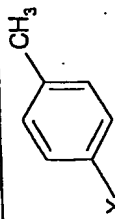

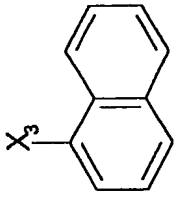
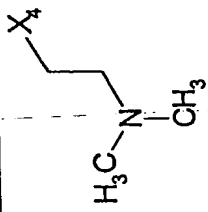
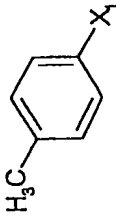

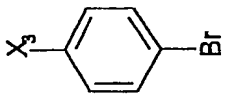
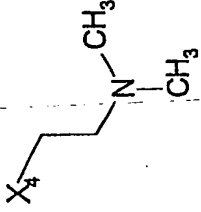
R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

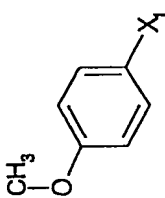
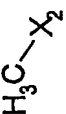
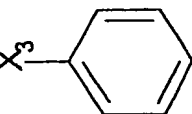
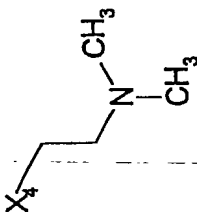

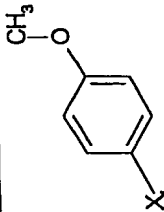
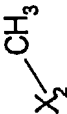
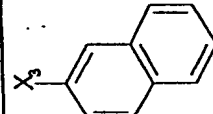
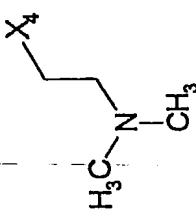

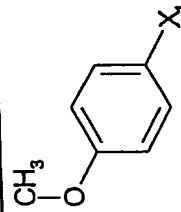
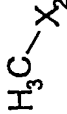
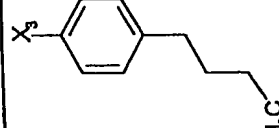
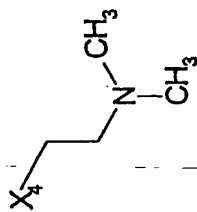

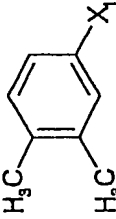
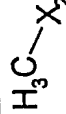
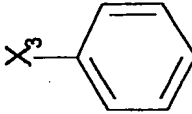
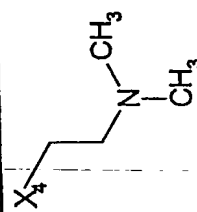
R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM



Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
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								%I > 35% @ 40 uM

Figure 3 (continued)

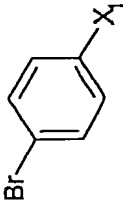


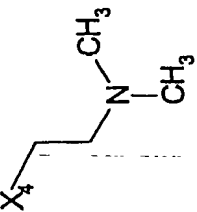
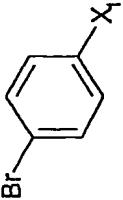

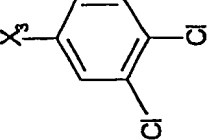
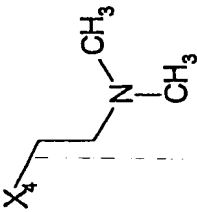
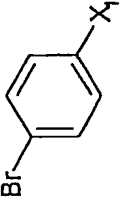

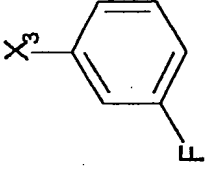
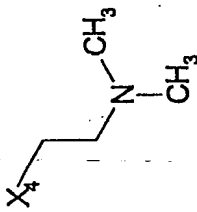
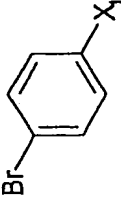

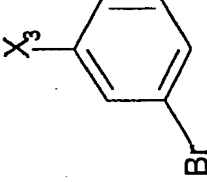
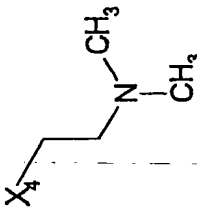
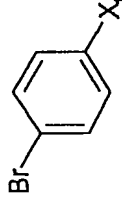

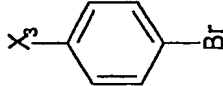
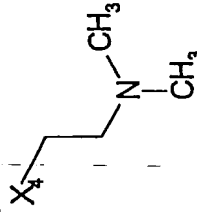
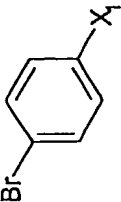
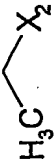
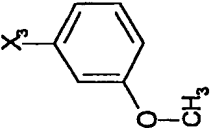
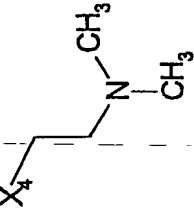
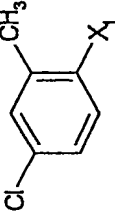
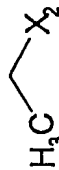
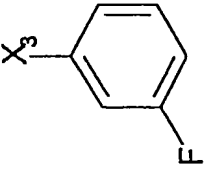
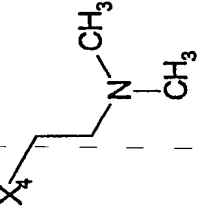
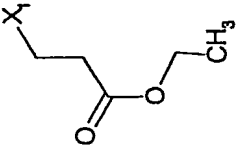

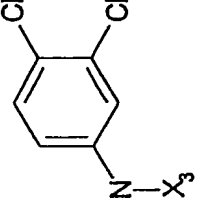
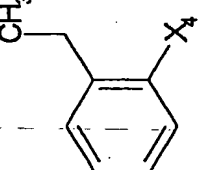
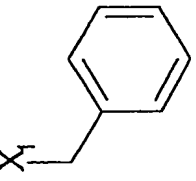
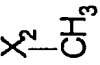
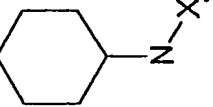
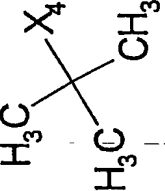
R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

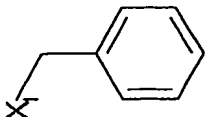
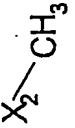
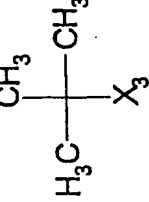
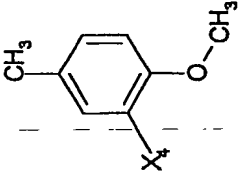
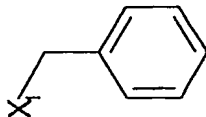
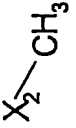
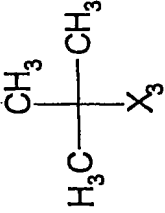
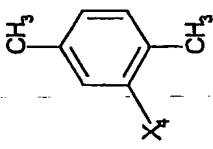
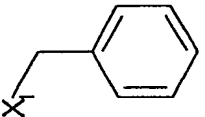
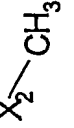
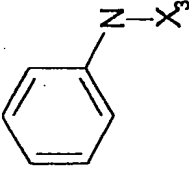
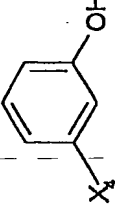
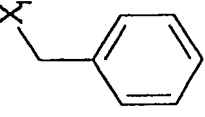

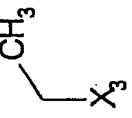
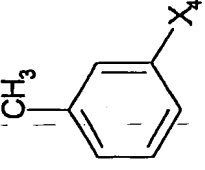
R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

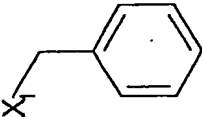
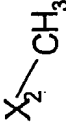
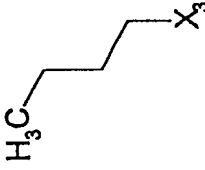
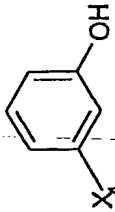
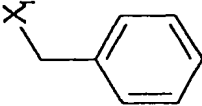

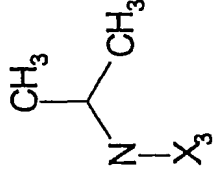
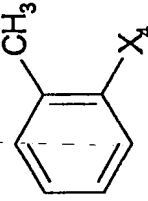
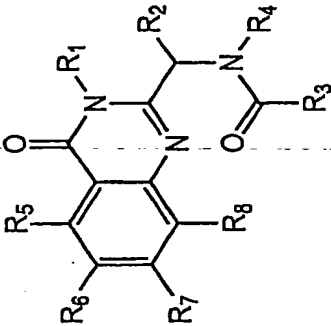
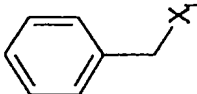

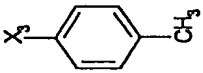
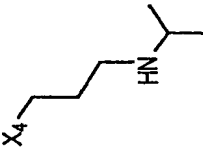

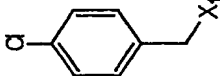


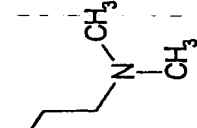

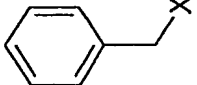


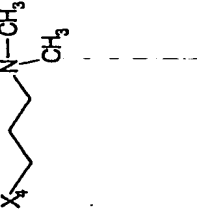

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

								
R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC <sub>50</sub> < 100 nM
								IC <sub>50</sub> < 100 nM
								IC <sub>50</sub> < 100 nM

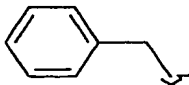

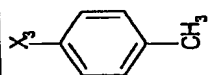
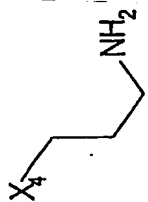

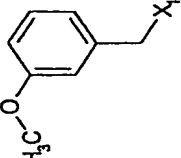

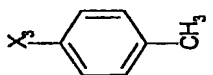
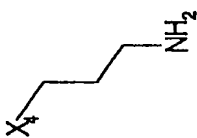

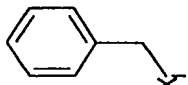


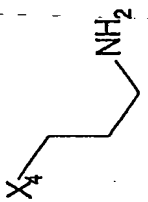

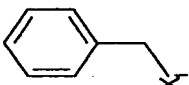
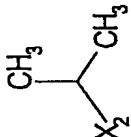
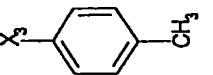
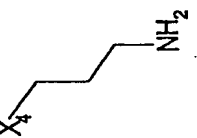

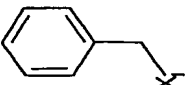
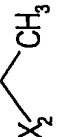
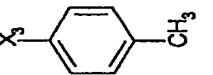
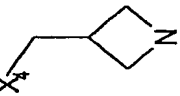

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM



Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

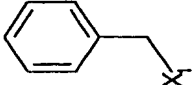

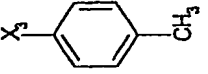
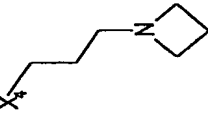

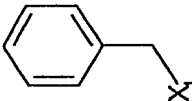

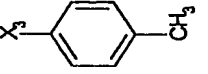
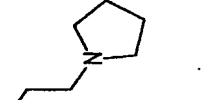

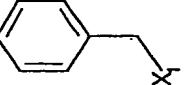

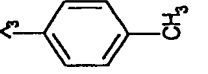
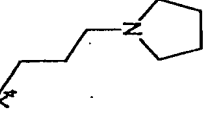

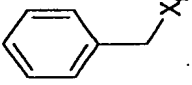


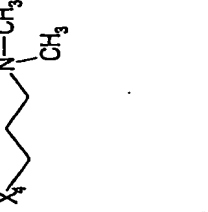

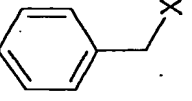
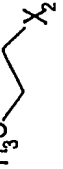
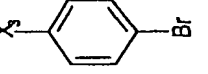
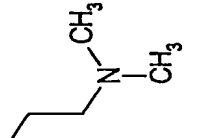

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC <sub>50</sub> < 100 nM
								IC <sub>50</sub> < 100 nM
								IC <sub>50</sub> < 100 nM
								IC <sub>50</sub> < 100 nM
								IC <sub>50</sub> < 100 nM



R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)

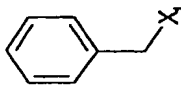


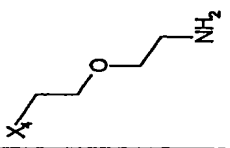

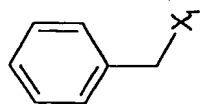

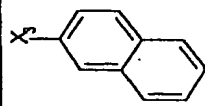
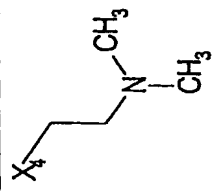

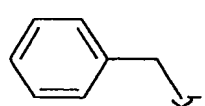
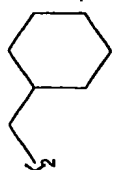
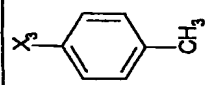
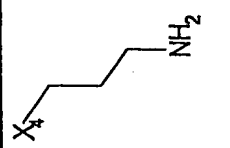

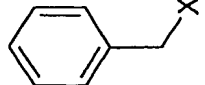

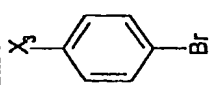
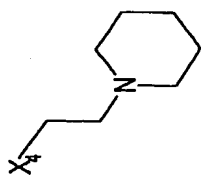

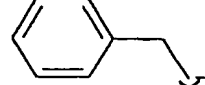

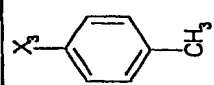
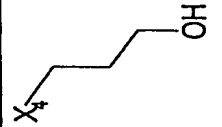

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM



Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

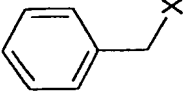


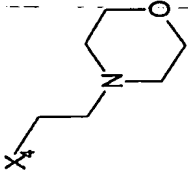

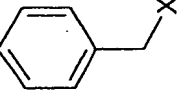

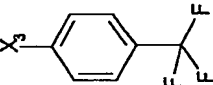
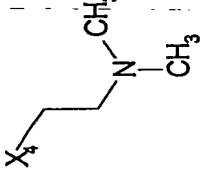

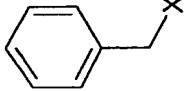

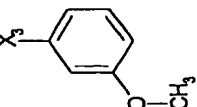
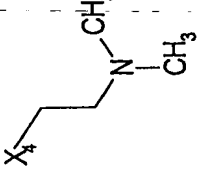

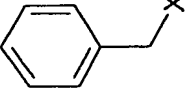

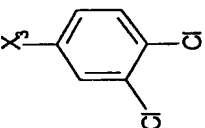
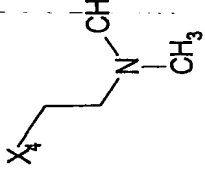

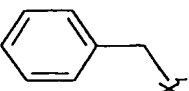

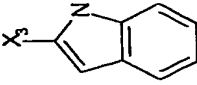
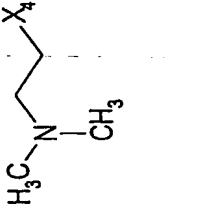

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM



Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

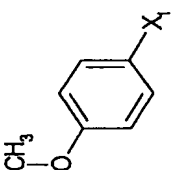

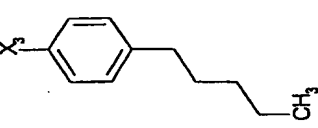
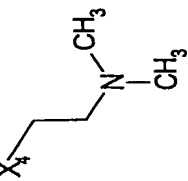

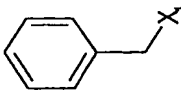

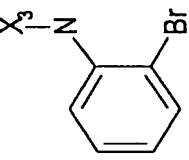
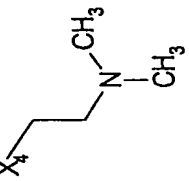
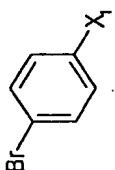

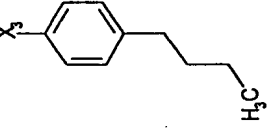
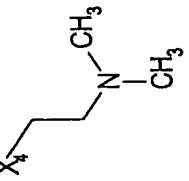
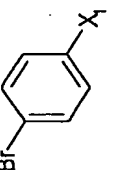

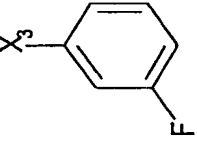
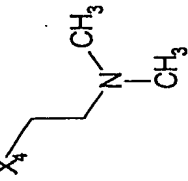
R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM



Figure 3 (continued)

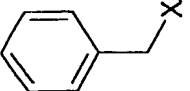

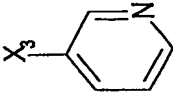
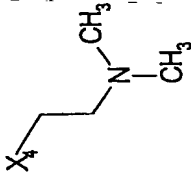

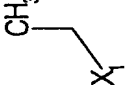
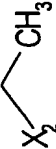
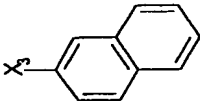
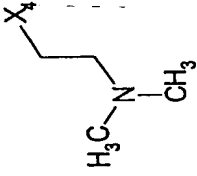

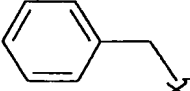

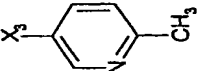
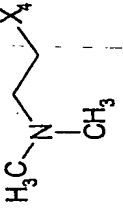

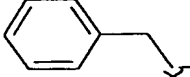
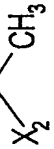
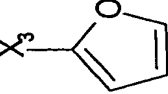
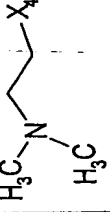

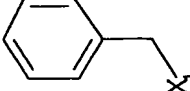

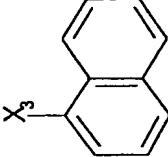
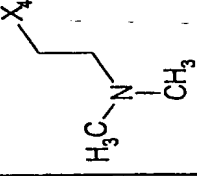
R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

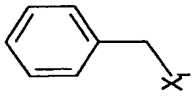

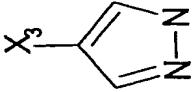
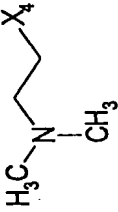

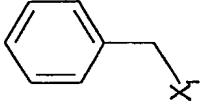
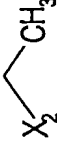
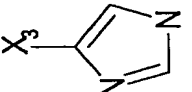
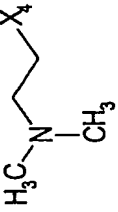

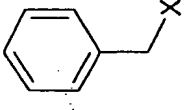
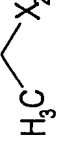
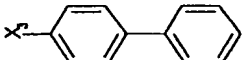
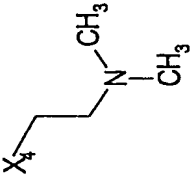
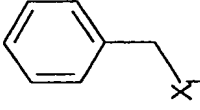


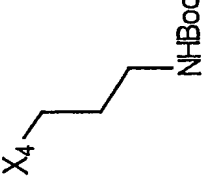

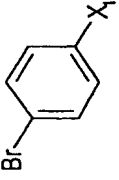

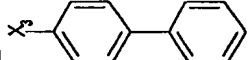
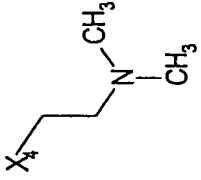
R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM

Figure 3 (continued)

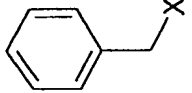

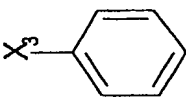
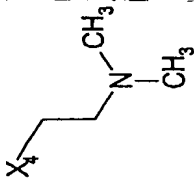
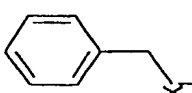

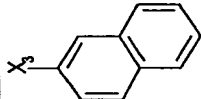
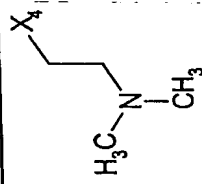
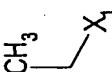


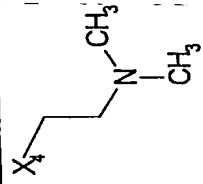

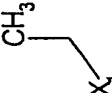

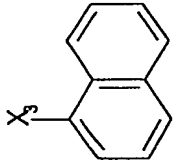
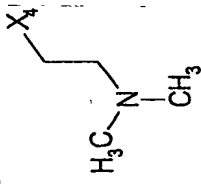

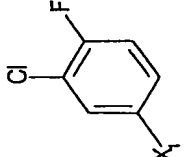

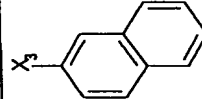
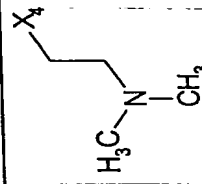
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								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM

Figure 3 (continued)

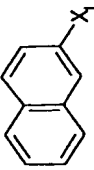


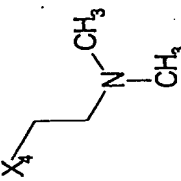
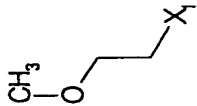


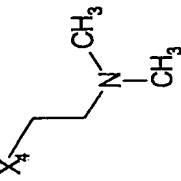
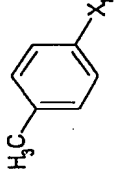
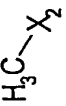

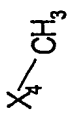

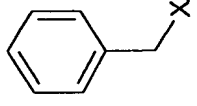

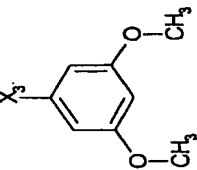
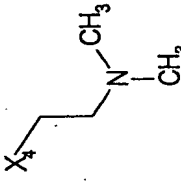
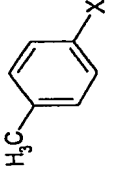
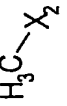
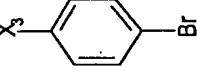


R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM



Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM

Figure 3 (continued)

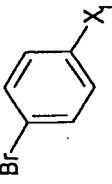
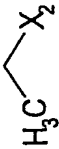
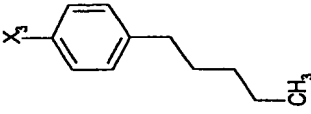
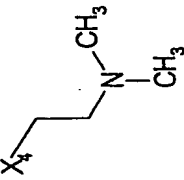
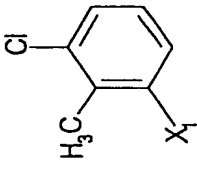

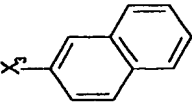
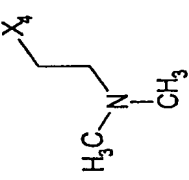
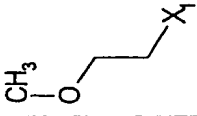

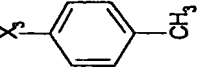
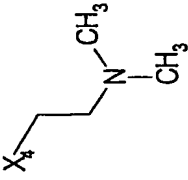
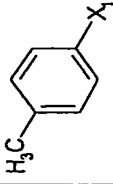
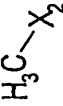

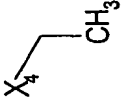

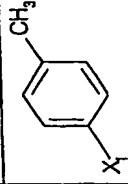
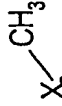
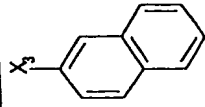
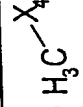

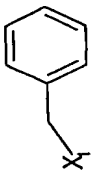
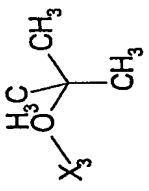
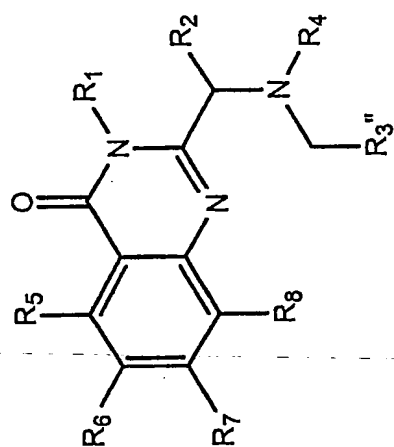
R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								IC50 = 10 uM-50 uM



R <sub>1</sub>	R <sub>2</sub>	R <sub>3''</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub> <sup>''</sup>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

Table 1: Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM



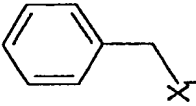

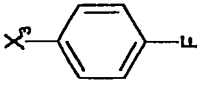
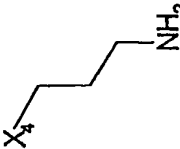

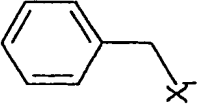

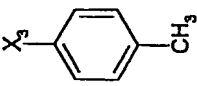
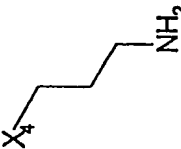

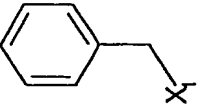

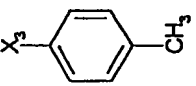
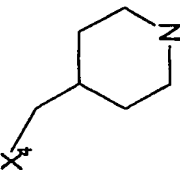

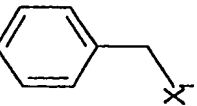


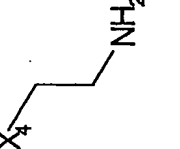

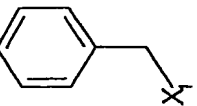

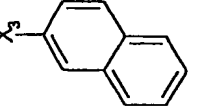
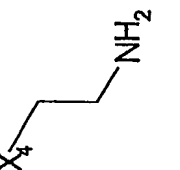

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub> "	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

Figure 3 (continued)

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub> "	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								KI < 100 nM
								KI < 100 nM
								KI < 100 nM
								KI < 100 nM
								KI < 100 nM

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub> <sup>''</sup>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki = 100 nM-1 uM
								Ki = 100 nM-1 uM

R <sub>1</sub>	R <sub>2</sub>	R <sub>3</sub>	R <sub>4</sub>	R <sub>5</sub>	R <sub>6</sub>	R <sub>7</sub>	R <sub>8</sub>	Activity
								K <sub>i</sub> = 100 nM-1 $\mu$ M
								K <sub>i</sub> = 100 nM-1 $\mu$ M
								K <sub>i</sub> = 100 nM-1 $\mu$ M
								K <sub>i</sub> = 1 $\mu$ M-10 $\mu$ M
								K <sub>i</sub> = 1 $\mu$ M-10 $\mu$ M



Figure 4: Asymmetric Synthesis

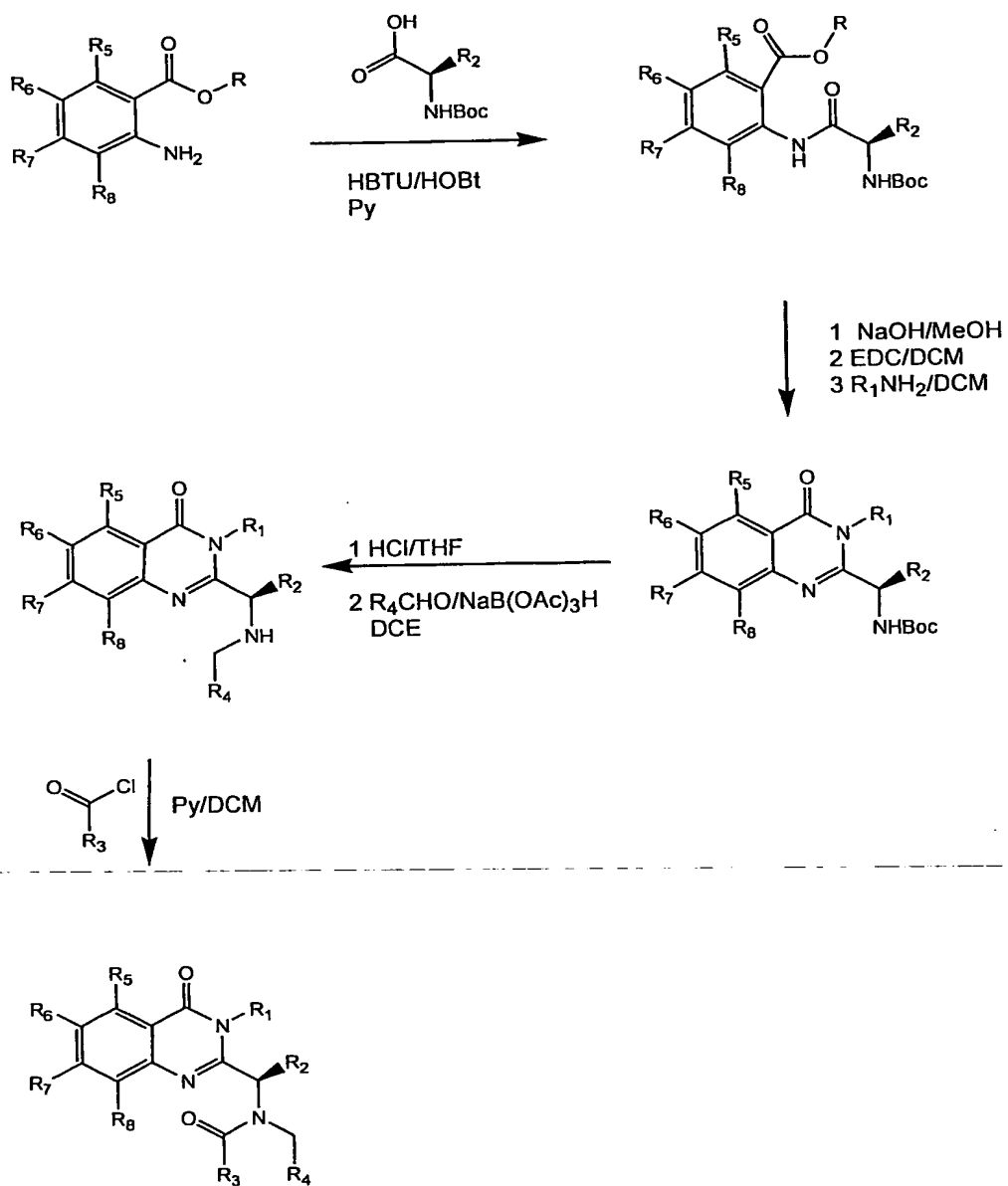
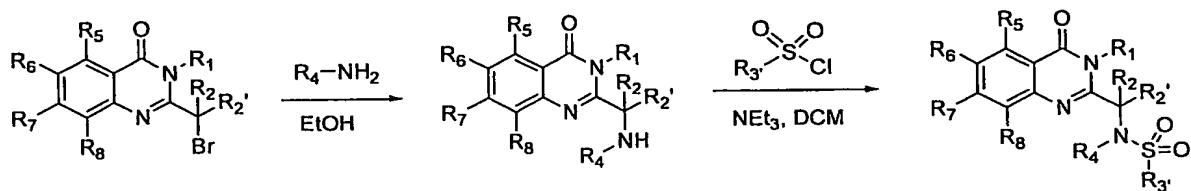


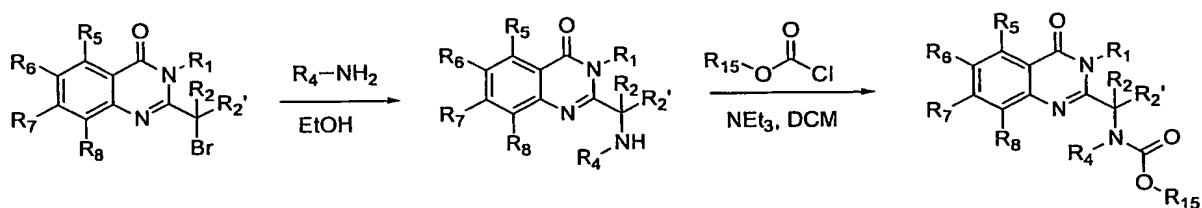
Figure 5

Figure 5a: Sulfonamide Synthesis



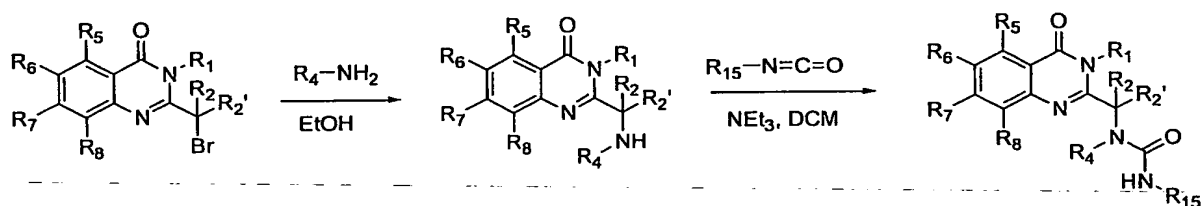
5

Figure 5b: Carbamate Synthesis



10

Figure 5c: Urea Synthesis



15 Figure 5d: Primary and Secondary Amine R4 Synthesis

